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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
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02/21/2002

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EAAM	IINER
HOGANS,	DAVID L
ART UNIT	PAPER NUMBER

DATE MAILED: 02/21/2002

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary		Application No.	Applicant(s)				
		09/763,365	TAKIZAWA ET AL.				
		Examiner	Art Unit				
		David L. Hogans	2813				
Period fo	The MAILING DATE of this communication app or Reply	ears on the cover sheet with the o	correspondence address				
A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION. Extensions of time may be available under the provisors of 37 CFR 1 19(a). In no event, however, may a reply be timely fried after SIX (6) MONTHS from the mailing date of this communication. If the period for reply septicled above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely. If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication of the specified above, the maximum statutory period will apply and will expire six (6) MONTHS from the mailing date of this communication. Any reply received by the Office stended protein for reply with, by sature cause the application to become ARANDONED (S C § 133). Any reply received by the Office SIM of the mailing date of this communication, even if timely filled, may reduce any earned patent term adjustment. See 37 CFR 1 704(b).							
1)[🛛	1) Responsive to communication(s) filed on <u>03 January 2002</u> .						
2a)	This action is FINAL . 2b)⊠ Thi	s action is non-final.					
3)	3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.						
Dispositi	on of Claims						
4)🖂	4) ☐ Claim(s) 1-4 and 14 is/are pending in the application						
	4a) Of the above claim(s) is/are withdraw	n from consideration.					
5)	5) Claim(s) is/are allowed.						
. —	6)⊠ Claim(s) <u>1-7 and 14</u> is/are rejected.						
7)	Claim(s) is/are objected to						
8) Claim(s) 8-13 are subject to restriction and/or election requirement.							
Application	on Papers						
9)☐ The specification is objected to by the Examiner							
10) ☐ The drawing(s) filed on 23 February 2001 is/are: a) ☐ accepted or b) ☐ objected to by the Examiner							
_	Applicant may not request that any objection to the	***					
11) ☐ The proposed drawing correction filed on is: a) ☐ approved b) ☐ disapproved by the Examiner.							
If approved, corrected drawings are required in reply to this Office action.							
12) ☐ The oath or declaration is objected to by the Examiner.							
Priority u	nder 35 U.S.C. §§ 119 and 120						
13) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).							
a) ⊠ All b) ☐ Some * c) ☐ None of							
	1 Certified copies of the priority documents	have been received.					
:	 Certified copies of the priority documents 	have been received in Application	on No				
	3 Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17 2(a)). *Souther Netherland Method (Office action for a little the perifficial points) and to receive the perifficial points.						
* See the attached detailed Office action for a list of the certified copies not received. 14) Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application)							
a) ☐ The translation of the foreign language provisional application has been received.							
15) Acknowledgment is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121.							
Attachment(s)							
2) Notice	of References Cited (PTO-892) of Draftsperson's Patent Drawing Review (PTO-948) ation Disclosure Statement(s) (PTO-1449) Paper No(s)		(PTO-413) Paper No(s) Patent Application (PTO-152)				

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DETAILED ACTION

Response to Traversal of Restriction

Per your January 3, 2002, response to restriction requirement. Examiner maintains these inventions are distinct because they have acquired a separate status within the art. As proof of this, the December 4, 2001, Election/Restriction Detailed Action cited different classifications for the claimed inventions. Therefore, since the different classifications provides an undue examining burden upon the Examiner, the Restriction Requirement is made final.

Claim Rejections - 35 USC § 102

 The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

Claim 1, 2 and 4 are rejected under 35 U.S.C. 102(b) as being anticipated by 5,101,247 to
 Ozturk et al.

In reference to Claim 1. Ozturk et al. teaches:

 a semiconductor device comprising: a silicon substrate, a MOSFET formed on the silicon substrate and a gate electrode of the transistor comprised by a germanium film (26). (See Figures 1, 2 and 3; column 7 lines 20-68) Art Unit: 2813

In reference to claim 2, Ozturk et al. teaches:

 a germanium film comprised by a polycrystalline germanium film (See column 4 lines 3-32; column 5 lines 52-60, column 0 lines 40-66)

In reference to claim 4. Ozturk et al. teaches:

- a multi-layer gate electrode with a low resistance conductive film (33) (See Figure 3; column 7 lines 20-68)
- 3. Claims 1, 3, 4, 7 and 14 are rejected under 35 U.S.C. 102(b) as being anticipated by 5,216,271 to Takagi et al.

In reference to Claim 1, Takagi et al. teaches:

 a semiconductor device comprising: a silicon substrate, a MOSFET formed on the silicon substrate and a gate electrode of the transistor comprised by a germanium film (8). (See Figure 1A; columns 2-3 lines 58-07)

In reference to Claim 3, Takagi et al. teaches:

 p-type impurities doped into said germanium film (See Figure 1A; columns 2-3 lines 58-07) In reference to claim 4, Takagi et al. teaches:

 a multi-layered gate electrode with a low resistance conductive film (10) (See Figure 1A: columns 2-3 lines 58-07)

In reference to claim 7, Takagi et al. teaches:

 a n-channel MOSFET and a p-channel MOSFET wherein a gate electrode of each MOSFET is comprised by a polysilicon germanium film (25 or 31) in which p-type impurities are doped (See Figures 2 and 3A to 3E, columns 4-5 lines 37-42)

In reference to Claim 14, Takagi et al. teaches:

 p-type impurities doped into said germanium film (See Figure 1A, column 2-3 lines 58-07)

Claim Rejections - 35 USC § 103

- 4. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title: if the differences between the subject matter sought to be patented and the prior at are asth skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- Claim 5 is rejected under 35 U.S.C. 103(a) as being unpatentable over 5,101,247 to
 Ozturk et al. in view of 5,608,249 to Gonzalez.

In reference to claim 5, Ozturk et al. teaches, a semiconductor device comprising a silicon substrate, a MOSFET formed on the silicon substrate and a gate electrode of the transistor comprised by a germanium film (26). (See Figures 1, 2 and 3; column 7 lines 20-68) Furthermore, Ozturk et al. teaches a multi-layer gate electrode with a low resistance conductive film (33). (See Figure 3; column 7 lines 20-68)

Ozturk et al. fails to explicitly teach that the low resistance conductive film is comprised by a transition metal, a transition metal silicide, or a transition metal nitride film, or a combination thereof.

However, Gonzalez, in Figure 4 and column 6 lines 6-17, discloses the concept of a low resistance conductive film (41) comprised by a transition metal silicide or a transition metal nitride film.

It would have been obvious to one of ordinary skill in the art to modify Ozturk et al.'s teachings via Gonzalez's teaching of a low resistance conductive film comprised by a transition metal silicide or a transition metal nitride film. Ozturk et al.'s modification via Gonzalez's teachings is obvious because this is a well known way to make ohmic contacts. Therefore, it would be well known to apply this conductive film composition to a Germanium layer.

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Claim Rejections - 35 USC § 103

6. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as whole would have been obvious at the time the invention was made to a person has ing ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claim 6 is rejected under 35 U.S.C. 103(a) as being unpatentable over 5,216,271 to
 Takagi et al. in view of 5,227,333 to Shepard.

In reference to claim 6, Takagi et al. teaches, a semiconductor device comprising a silicon substrate, a MOSFET formed on the silicon substrate and a gate electrode of the transistor comprised of a germanium film (8). (See Figures 1A; columns 2-3 lines 58-07) Furthermore. Takagi et al. teaches a multi-layer gate electrode with a low resistance conductive film (10). (See Figure 1A; columns 2-3 lines 58-07)

Takagi et al. fails to explicitly teach a multi- layer structure with a polysilicon layer in between a germanium layer and a conductive layer.

However, Shepard, in Figure 6 and columns 4-5 lines 65-10, discloses the concept of a multi-layer structure with a polysilicon layer (76') in between a germanium layer (74') and a conductive layer (76').

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It would have been obvious to one of ordinary skill in the art to modify Takagi et al.'s teachings via Shepards teaching of a multi-layer structure with a polysilicon layer in between a germanium layer and a conductive layer. Takagi et al.'s modification via Shepards teachings is obvious because silicide layers are known to provide low resistance contacts. Therefore, it would be well known to apply this conductive film composition (polysilicon and metal) to a Germanium layer.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to David L. Hogans whose telephone number is (703) 305-3361. The examiner can normally be reached on M-F (7:30-4:30).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri can be reached on (703) 306-2794. The fax phone numbers for the organization where this application or proceeding is assigned are (703) 308-7722 for regular communications and (703) 308-7724 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number ja-(703) 308-1782.

Douglas Wille

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February 11, 2002